

L Number	Hits	Search Text	DB	Time stamp
99	6773	silicon?on?insulat\$3	USPAT; US-PGPUB	2004/04/13 15:02
100	12731	SOI	USPAT; US-PGPUB	2004/04/13 15:02
101	30611	test\$3 near2 (structure\$1 or wafer\$1 or substrate\$1)	USPAT; US-PGPUB	2004/04/13 15:04
102	9445	monitor\$3 near2 (structure\$1 or wafer\$1 or substrate\$1)	USPAT; US-PGPUB	2004/04/13 15:04
103	28588	cmp	USPAT; US-PGPUB	2004/04/13 15:04
104	25029	(chemical\$2 near mechanical\$2) adj polish\$3	USPAT; US-PGPUB	2004/04/13 15:05
105	3732	(chemical\$2 near mechanical\$2) adj planariz\$5	USPAT; US-PGPUB	2004/04/13 15:05
106	12297	etch\$3 adj stop	USPAT; US-PGPUB	2004/04/13 15:05
107	11696	trench near isolation	USPAT; US-PGPUB	2004/04/13 15:05
108	8047	STI	USPAT; US-PGPUB	2004/04/13 15:05
109	31	((test\$3 near2 (structure\$1 or wafer\$1 or substrate\$1) ) or (monitor\$3 near2 (structure\$1 or wafer\$1 or substrate\$1) )) and (silicon?on?insulat\$3 or SOI) and ((trench near isolation) or STI) and (etch\$3 adj stop)	USPAT; US-PGPUB	2004/04/13 15:14
110	21915	trench\$2 near2 form\$5	USPAT; US-PGPUB	2004/04/13 15:16
112	12	(monitor\$3 same (trench\$2 near2 form\$5)) and (silicon?on?insulat\$3 or SOI)	USPAT; US-PGPUB	2004/04/13 15:17
111	113	monitor\$3 same (trench\$2 near2 form\$5)	USPAT; US-PGPUB	2004/04/13 15:30